

FORM PTO-1449

**INFORMATION DISCLOSURE CITATION  
IN AN APPLICATION**

(Use several sheets if necessary)

Docket Number (Opti nal)  
81784.0291Application Number  
Not Assigned [parent 09/291,538]

Applicant

Hidenori OGATA et al.

Filing Date  
November 14, 2003Group Art Unit  
Not Assigned**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
My	5,432,122	07/1995	Chae			
	5,496,768	03/1996	Kudo			
	4,234,358	11/1980	Celler et al.			
	5,365,875	11/1994	Asai et al.			
	5,683,935	11/1997	Miyamoto et al.			
	5,529,951	06/1996	Noguchi et al.			
	5,591,668	06/1997	Maegawa et al.			
	4,514,895	05/1985	Nishimura			
	5,815,494	09/1998	Yamazaki et al.			
	5,767,003	06/1998	Noguchi			
	5,454,347	10/1995	Shibata et al.			
	5,533,040	07/1996	Zhang			
My	6,274,414	08/2001	Ogata et al.			

**FOREIGN PATENT DOCUMENTS**

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

My	M. Kamiya et al., "Eximer Laser Annealing SLA3600," pp. 24-25 with its English translations and Document 1 (Electronic Display Forum '96 program cover sheet, April 17-19, 1996) and Document 2 (List of presentations at Forum '96, including "Eximer Laser Annealing System SLA3600, April 19, No. 18) showing the laid open date of 4/17-4/19/1996
My	Mamoru Furuta et al., "Bottom-Gate Poly-Si Thin Film Transistors Using XeCl Excimer Laser Annealing and Ion Doping Techniques," IEEE Transactions on Electron Devices, vol. 40, No. 11, November, 1993

EXAMINER

*Quincy Wong*

DATE CONSIDERED

*9/2004*

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.